

Free-Charge Carrier Profiles of Iso- and Anisotype Si Homojunctions

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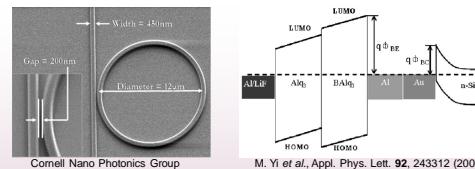
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Our Message

- We demonstrate the first desktop THz ellipsometer in the frequency range from 0.1 to 1.5 THz (~ 3 to 50 cm^{-1}) using a rotating analyzer configuration and a tunable backward wave oscillator source.
- THz ellipsometry enables optical determination of low (!) ($\sim 10^{15} \text{ cm}^{-3}$) free charge carrier concentrations in silicon bulk and layered structures.
- THz ellipsometry can be used to accurately find the location of an abrupt isotype ($p+/p$ or $n-/n$) homojunction as well as the diffused carrier concentration profile.
- Simultaneous analysis of THz and FIR data allows contact-free, non-destructive measurement of complex semiconductor structures.

Motivation

- Optical sensitivity to low carrier concentration levels via THz resonance polaritons provides a new technique to study complex semiconductor structures
- Non-destructive, contact-free determination of semiconductor structure is key to developing future technologies
- Integrated Circuit waveguides for photonic computation and integration with optical fiber communications
- High mobility transistors
- Silicon homojunction interfacial workfunction internal photoemission (HIWIP) far-infrared detectors

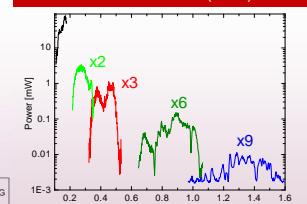


THz Ellipsometry Setup



- Patent application filed with UNL, Sept. 2008
- Rotating analyzer (A)
 - Golay detector (GC)
 - Polarization Rotator (PR)

Backwards Wave Oscillator (BWO) Source



Model System

Spectral Features

- The low THz region is dominated by surface guided waves, present here at $\sim 290 \text{ GHz}$ and $\sim 900 \text{ GHz}$.
- The FIR region is dominated by Fabry – Perot oscillations, which damp at high frequency.

Analytical Model

Analytical solution to Poisson equation of an isotype homojunction [1]:

$$E^2(\phi) = -2/(\varepsilon_0 \varepsilon) \int \rho(\phi) d\phi$$

Assuming semi infinite boundary conditions and substituting the non-degenerate semiconductor expressions:

$$N(x) = N_D e^{[q\phi(x)/kT]} \quad P(x) = N_A e^{[q\phi(x)/kT]}$$

Results in a simplified equation if $N_+ \gg N_-$, where $N(x)$ may be determined entirely in terms of N_+ and N_- and a characteristic length L !

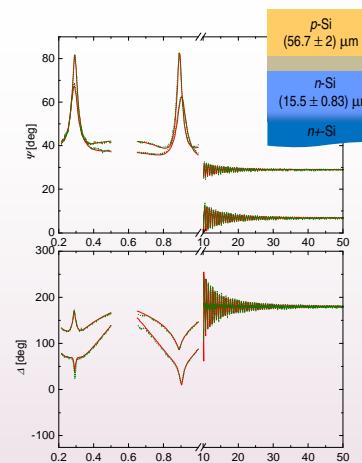
$$N_H(x) = N_+ e^{-\left[\frac{LN(N_+/N_-)}{1+q\sqrt{N_+/N_-}}\right]e^{x/L}}$$

$$N_L(x) = N_- e^{\left[LN\left(\frac{N_+}{N_-}\right) - 2LN\left(e^{0.5\left(1-\frac{N_- LN(N_+/N_-)}{N_+ + N_-} + x/L\right)}\right)\right]}$$

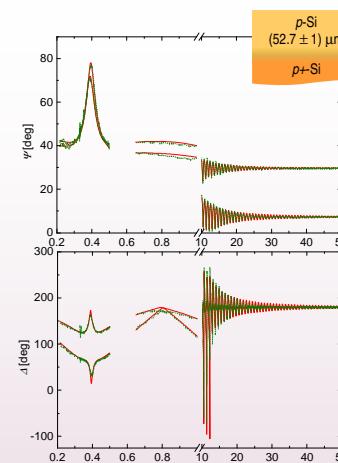
Separate solutions for each side of the abrupt junction lead to an asymmetric carrier profile. Mobility is also given as a function of concentration [2].

$$\mu = \mu_{min} + \frac{\mu_{max} - \mu_{min}}{1 + \left(\frac{x}{N_{ref}}\right)^{\alpha}}$$

P/N/N+ Sample

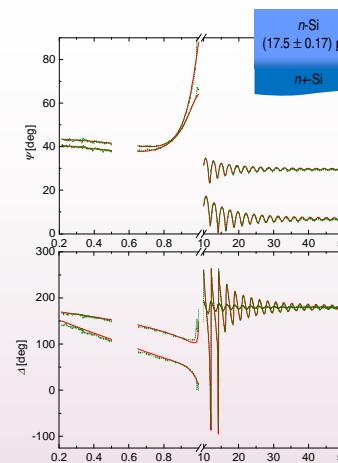


P/P+ Sample

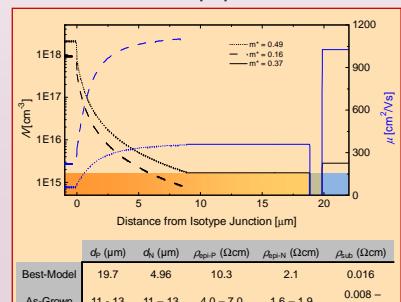
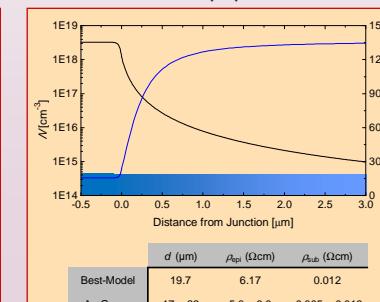
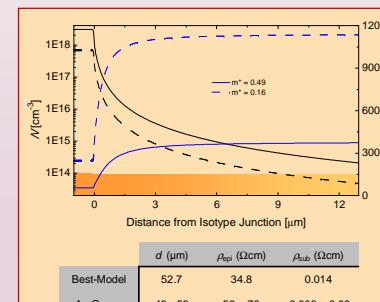
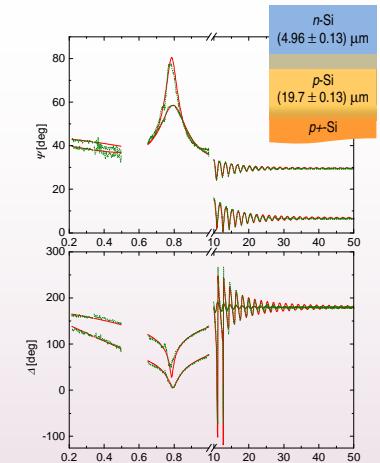


Silicon Iso- and Anisotype Example Systems

N/N+ Sample



N/P/P+ Sample



[1] Z.T. Kuznicki, J. Appl. Phys. **69**, 6526 (1991)

[2] C. Jacoboni et al., Solid-State Electron. **20**, 77 (1976)